FORM PTO-1449/A and B (Modified)	APPLICATION NO.: Unassigned	ATTY. DOCKET NO.: S1022.81053US00
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	FILING DATE: Herewith	CONFIRMATION NO.: Unassigned
	APPLICANT: S1022.81053US00	
Sheet 1 of 1	GROUP ART UNIT: Unassigned	EXAMINER: Unassigned

U.S. PATENT DOCUMENTS

Examiner's Initials	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YYYY
		Number	Kind Code		
PB	*	4,933,733		Iranmanesh et al.	06/12/90

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Examiner's Initials	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document (not necessary)	Date of Publication of Cited Document MM-DD-YYYY	Translation (Y/N)
		Office/ Country	Number	Kind Code			

OTHER ART — NON PATENT LITERATURE DOCUMENTS

Examiner's Initials	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)	
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EXAMINER	DATE CONSIDERED
	11/11/04

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